Preface

Rapid advances in the fields of micro/nanoscale science, engineering and technology have allowed us to create and manipulate devices and systems at ever-shrinking dimensions. As to address the growing interests and share the exciting accomplishments in these areas, the emphasis of this symposium is on Nanoelectromechanical Systems (NEMS) / Microelectro-mechanical Systems (MEMS) and Micro Total Analysis Systems (µTAS), with the purpose of exploring new devices, process innovation and their engineering applications.

NEMS/MEMS and µTAS have a wide range of applications in diverse areas of science and technology. Being interdisciplinary in nature, they draw upon expertise from numerous technical areas. In this symposium G, the articles highlight various topics in the following areas:

- Theory, Design and Analysis of NEMS/MEMS
- NEMS/MEMS Fabrication Technologies
- Sensors, Actuators and Microsystems
- RF MEMS Devices and Characterization
- Microfluidics and Micro Total Analysis Systems (µTAS)
- Nanotechnology and Nano Devices
- Optical MEMS, Nanophotonic and Plasmonics

We are very fortunate to host 20 distinguished speakers from Singapore, France, Taiwan, Hong Kong, Australia, United Kingdom and the United States. We extend our sincere thanks to the speakers for sharing us with wide-ranging knowledge in the fields of NEMS/MEMS technology.

The organizers of this symposium wish to express thanks and appreciation to all the distinguished speakers, as well as the authors who have contributed with their works and shared us their knowledge in the Proceedings.

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